

(19)



JAPANESE PATENT OFFICE

# PATENT ABSTRACTS OF JAPAN

(11) Publication number: 08102544 A

(43) Date of publication of application: 16.04.1996

(51) Int. Cl. H01L 29/84  
H01L 21/316, H01L 41/08

(21) Application number: 06271936  
(22) Date of filing: 29.09.1994

(71) Applicant: SATO YOICHI  
(72) Inventor: SATO YOICHI

## (54) MICROMACHINE WITH METALLIC ANODIZED FILM

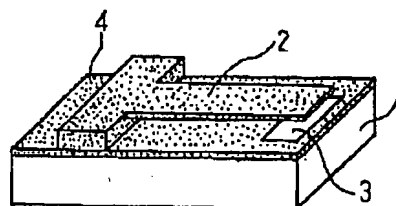
### (57) Abstract:

**PURPOSE:** To provide a micromachine wherein an insulator obtained by anodizing metal is used for a structure body.

**CONSTITUTION:** A structure body and a moving part are constituted on a substrate such as a semiconductor by using an insulator obtained by anodizing metal as a material. The selection figure is one example wherein a substrate 1, a supporting part partially connected and a beam 2 connected thereto exist. The beam is separated from a substrate and bends and vi-

brates by an external pressure, a voltage applied to an electrode 3 in the selection figure. The above is one example, and various fine machinery devices can be acquired by combination of an insulator obtained by anodizing metal and making a resin material a sacrificial layer.

COPYRIGHT: (C)1996,JPO



BB1